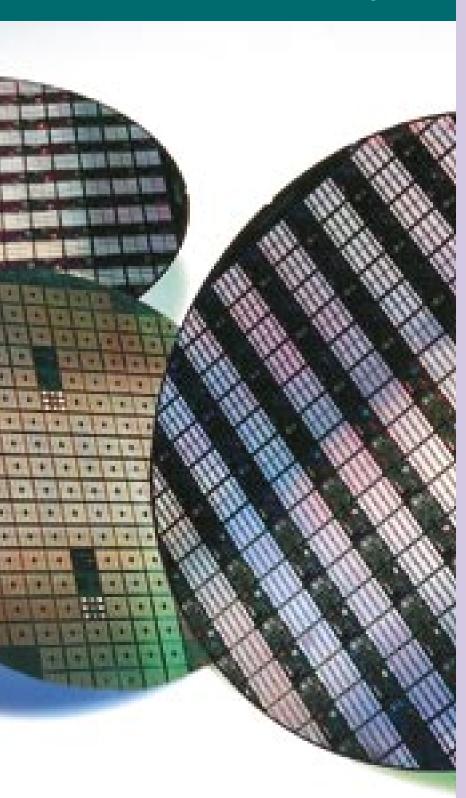
Positive DUV Photoresist

UV110[™] Series



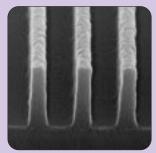
Advanced Resists for 130 nm Design Rules



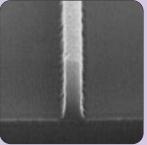
UV110 Series photoresists are multi-functional, DUV photoresists designed for 130 and 150 nm applications.

Features include:

- Large process windows, including DOF:
 - ≥1.0 μm @ 150 nm 1:1.5 lines/spaces
 - ≥0.6 μ m @ 150 nm isolated lines
 - ≥1.0 μm @ 150 nm 1:1 lines/spaces
- Maximum isolated line film retention to <110 nm
- Excellent CD uniformity of <9 nm @ 140 nm 1:2 lines/spaces



1:1.5 Lines/Spaces @ 130 nm



Isolated Line @ 130 nm

UV110 0.60 NA, AR3™

Contact your local Shipley representative for more information on these and other Shipley products.

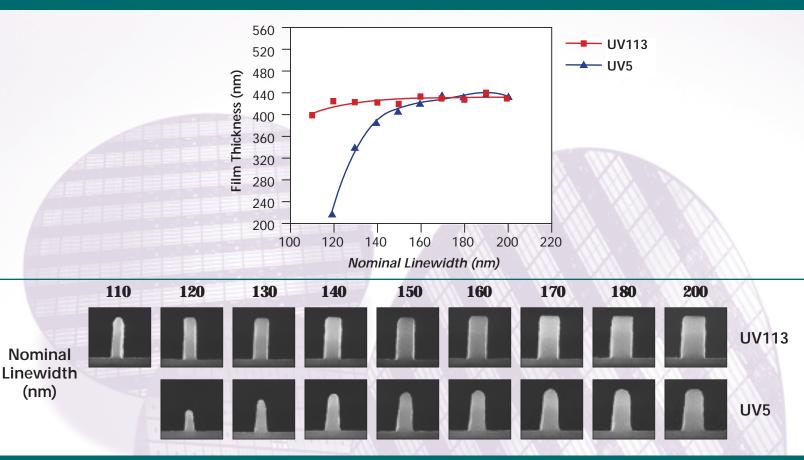


455 Forest Street, Marlborough, MA 01752 TL: 800.832.6200 FX: 508.485.9113

Positive DUV Photoresist UV110 Series



Isolated Line Film Retention



CD Uniformity

